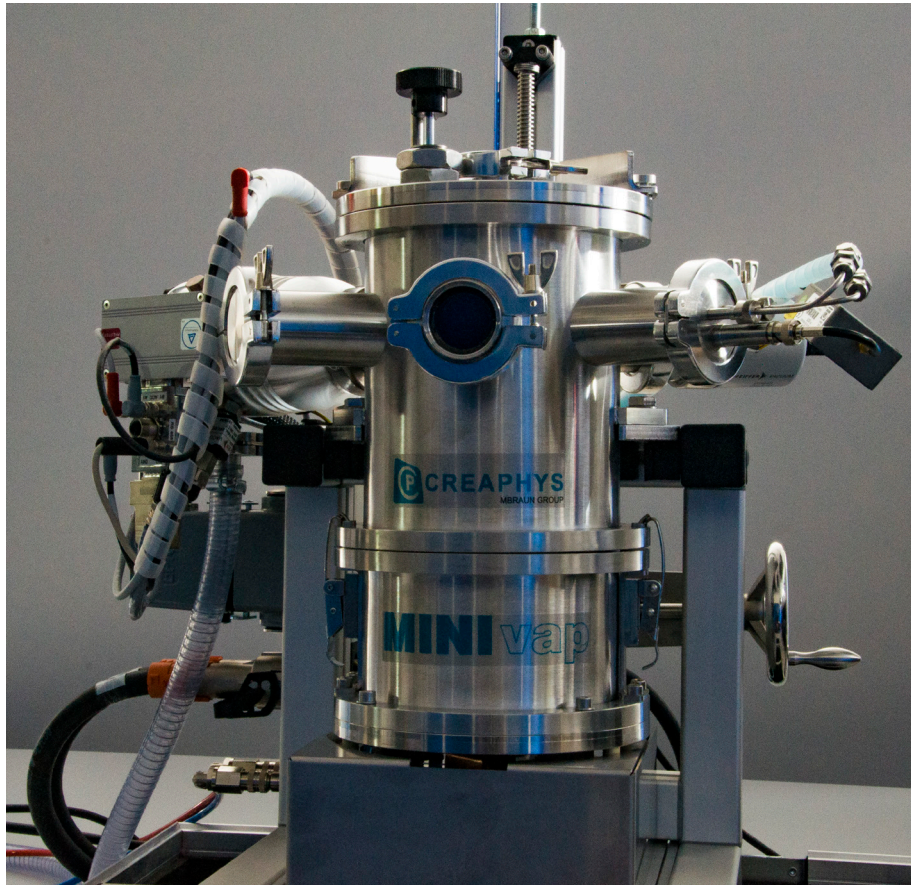


MINIvap

MINI-DEPOSITION TOOL



- Compact design
- Can be integrated in existing MBRAUN gloveboxes
- Economic solution
- Short delivery time
- Fast and easy installation
- Applications:
 - Metallization, contact layers
 - Organic and inorganic compounds (e.g. OFET, Bio-Tech)
 - Microscopy
 - Semiconductor

MINIvap

MINI-DEPOSITION TOOL

DESCRIPTION

MBRAUN's mini-deposition tool consists of a dry turbo-molecular pump system with up to 70 l/sec (Pfeiffer, HiPace80) and a single button operation. The MINIvap generates a base pressure less than $5e-6$ mbar. The chamber is composed of stainless steel with a diameter of 150 mm, an exchangeable liner can be mounted as an option.

It may be integrated into existing MBRAUN gloveboxes, but can also be used as a stand-alone system.

It is possible to deal with substrate sizes up to 50x50mm. The loading process is manual.

The MINIvap can be additionally equipped with a range of mask and substrate holders, as well as a substrate shutter. Furthermore a temperature control of substrate heating/cooling can be added.

DEPOSITION SOURCES

Up to 2x thermal source (metal boat or ceramic boat with crucible), incl. controller

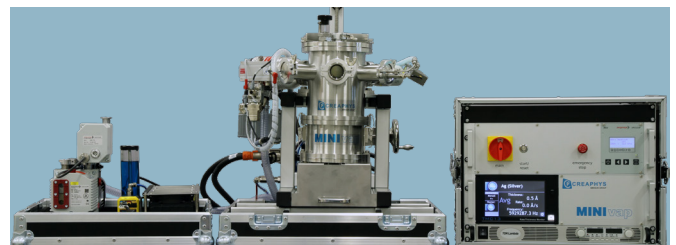
Up to 3 LTE (50-800°C) and HTE sources (300-1400°C) incl. controller

QCM Rate monitor (optional: 2nd QCM with dual channel), co-deposition possible

Layer uniformity < +/- 5 %

Limited to a substrate 50x50mm diameter

Optional: source shutter for LTE and HTE



SYSTEM SETUP

Stand-alone (bench-top)

Glovebox integration for existing boxes (easy retrofit)

SPECIFICATIONS

Base pressure < $5e-6$ mbar

Chamber diameter 150mm

Substrate size up to 50x50mm

Substrate shutter (manual or pneumatic)

Masking

Manual handling

